



In Re Application of:

Peter Wolters

Application No.:

09/523,115

Filed:

March 10, 2000

For:

DOUBLE DISK POLISHING MACHINE,

PARTICULARLY FOR TOOLING

SEMICONDUCTOR WAFERS

Examiner:

(Not yet assigned)

Group Art Unit:

Assistant Commissioner for Patent Washington, D.C. 20231

TC 3700 MAIL 30 2010 Docket No.: H01.2-89841

INFORMATION DISCLOSURE STATEMENT

Applicant submits herewith patents, publications or other information of which he is aware, and which he believes may be material to the examination of this application.

This Information Disclosure Statement is not intended to constitute an admission that any patent, publication or other information referred to herein is "prior art" to the invention of the above-identified application, unless specifically designated as such.

The filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information exists.

This Information Disclosure Statement is being filed within three months of the filing date of this application or date of entry into the national stage of an international

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application or before receipt of a first Official Action on the merits, whichever occurs last. A statement of relevancy of DE 195 47 085 is enclosed.

Respectfully submitted,

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Date: May 23, 2000

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